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90 12/20/2005		EXAM	EXAMINER	
TRASK BRITT		LOUIE, WAI SING		
ITY, UT 84110		ART UNIT	PAPER NUMBER	
		2814		
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DATE MAILED: 12/20/2005

Please find below and/or attached an Office communication concerning this application or proceeding.

				<u> </u>		
		Application No.	Applicant(s)			
		10/690,399	WILLIFORD, ETHAN			
	Office Action Summary	Examiner	Art Unit	-		
		Wai-Sing Louie	2814			
Period fo	The MAILING DATE of this communication app or Reply	ears on the cover sheet with the c	orrespondence address	••		
WHIC - Exte after - If NC - Failt Any	IORTENED STATUTORY PERIOD FOR REPLY CHEVER IS LONGER, FROM THE MAILING DYNAMINS OF SIX (6) MONTHS from the mailing date of this communication. O period for reply is specified above, the maximum statutory period ware to reply within the set or extended period for reply will, by statute, reply received by the Office later than three months after the mailing led patent term adjustment. See 37 CFR 1.704(b).	ATE OF THIS COMMUNICATION 36(a). In no event, however, may a reply be tim vill apply and will expire SIX (6) MONTHS from cause the application to become ABANDONE	N. nely filed the mailing date of this communic D (35 U.S.C. § 133).			
Status						
1)⊠	Responsive to communication(s) filed on 06 De	ecember 2005.				
2a) <u></u> ☐	This action is FINAL. 2b)⊠ This action is non-final.					
3)	Since this application is in condition for allowance except for formal matters, prosecution as to the merits is					
	closed in accordance with the practice under E	x parte Quayle, 1935 C.D. 11, 45	i3 O.G. 213.			
Disposit	ion of Claims					
5)□ 6)⊠ 7)□	Claim(s) <u>1-29</u> is/are pending in the application. 4a) Of the above claim(s) <u>10-29</u> is/are withdraw Claim(s) is/are allowed. Claim(s) <u>1-9</u> is/are rejected. Claim(s) is/are objected to. Claim(s) are subject to restriction and/or	n from consideration.				
Applicat	ion Papers					
10)	The specification is objected to by the Examine The drawing(s) filed on is/are: a) access Applicant may not request that any objection to the Replacement drawing sheet(s) including the correct The oath or declaration is objected to by the Ex	epted or b) objected to by the Eddrawing(s) be held in abeyance. See ion is required if the drawing(s) is obj	e 37 CFR 1.85(a). lected to. See 37 CFR 1.1			
Priority (under 35 U.S.C. § 119					
12) [a)	Acknowledgment is made of a claim for foreign All b) Some * c) None of: 1. Certified copies of the priority documents 2. Certified copies of the priority documents 3. Copies of the certified copies of the priority application from the International Bureau See the attached detailed Office action for a list	s have been received. s have been received in Applicati ity documents have been receive ı (PCT Rule 17.2(a)).	on No ed in this National Stage	?		
	ce of References Cited (PTO-892)	4) Interview Summary				
3) 🔲 Infor	ce of Draftsperson's Patent Drawing Review (PTO-948) mation Disclosure Statement(s) (PTO-1449 or PTO/SB/08) er No(s)/Mail Date	Paper No(s)/Mail Da 5) Notice of Informal P 6) Other:	atent Application (PTO-152)			

Application/Control Number: 10/690,399

Art Unit: 2814

DETAILED ACTION

Claim Rejections - 35 USC § 103

The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.

Claims 1-3 and 5-9 are rejected under 35 U.S.C. 103(a) as being unpatentable over Lilja et al. (US 5,286,981), newly cited.

With regard to claims 1-2 and 5, Lilja et al. disclose a power semiconductor device M₁ (col. 5, line 9 to col. 10, line 23 and fig. 1), comprising:

- Spaced-apart source and drain regions 2 formed in the substrate 1 (fig. 1);
- A channel region 7 defined between the source and drain regions 2 (fig. 1);
- A layer of gate oxide 3 formed over at least part of the channel region 7 (col. 5, line 53);
- A gate G₁ formed over the gate oxide 3, the gate further having at least one implant aperture formed there (col. 9, lines 17-42 and fig. 4), the channel region between the source and drain regions 2 of the substrate 1 further including a channel internal implanted region 7 between the source and drain regions (fig. 1), the source and drain regions 2 each including lightly doped extensions 6 under the gate G₁, but Lilja et al. do not disclose the lightly doped extensions 6 and the channel internal implanted region 7 being substantially equivalently doped.

However, since the applicant has not established the criticality of the doping concentration stated and since these concentrations are in common use in similar devices in the art, it would have been obvious to one of ordinary skill in the art to use these values in the device. Where patentability is said to be based upon particular chosen dimension or upon another variable recited in a claim, the applicant must show that the chosen dimensions are critical. In re Woodruff, 919 F2d 1575, 1578, 16 USPQ2d 1934, 1936 (Fed. Cir. 1990).

Page 3

With regard to claims 3 and 6, although, Lilja et al. do not specifically state that the channel internal implanted region and the lightly doped structure comprise double-diffusion structure. However, since Lilja et al. disclose both structures are formed by double-implantation IM2 and IM3 (col. 9, lines 17-32 and fig. 4c to 4d), it is clear that such a structure results in double-diffusion into the channel area and is thus an obvious feature of the claimed semiconductor device.

With regard to claim 7, Lilja et al. disclose the at least one lightly doped structure is a light-doped drain structure arranged between one of the drain and source regions 2 and the channel region 7 (fig. 1).

With regard to claims 8-9, Lilja et al. disclose the at least one implant aperture comprises a plurality of implant apertures arranged in a two dimensional array in a checkerboard configuration along the gate (fig. 2c).

Claim 4 is rejected under 35 U.S.C. 103(a) as being unpatentable over Lilja et al. (US 5,286,981) in view of Lai et al. (US 6,649,461).

Application/Control Number: 10/690,399

Art Unit: 2814

With regard to claim 4, Lilja et al. do not disclose the double-diffused structure 7 is implanted at a diagonal angle to the gate through the implant aperture. However, Lai et al. disclose an angle implant (Lai col. 8, lines 28-36 and fig. 4). Lai et al. teach the angle implant would reduce or eliminate the effects of narrow channel impurity diffusion to surrounding region of insulation (Lai col. 5, lines 48-51), which could cause the hot-carrier effect of the transistor (Lai col. 4, lines 20-35). Yilmaz et al. and Lai et al. have substantially the same environment of transistor having an oxide layer under the gate. Therefore, it would have been obvious for the one with ordinary skill in the art to modify Lilja's device with the teaching of Lai et al. to provide the angle implant through the gate implant aperture in order to avoid damaging the gate insulation.

Page 4

Response to Arguments

Applicant's arguments with respect to claims 1-9 have been considered but are moot in view of the new ground(s) of rejection in view of newly cited reference.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Wai-Sing Louie whose telephone number is (571) 272-1709. The examiner can normally be reached on 7:30 AM to 4:00 PM.

Application/Control Number: 10/690,399

Art Unit: 2814

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Wael Fahmy can be reached on (571) 272-1705. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Wai-Sing Louie

Page 5

Patent Examiner

Wsl

December 13, 2005.